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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Hitoshi KATO, et al.

Serial No. : 10/066,627

Filed : February 6, 2002

Art Unit : 2822

Examiner : Maria F. Guerrero

For : A Precleaning Method of Precleaning a Silicon Nitride Film Forming System (as amended)

LETTER WITH PROPOSED DRAWING CHANGES

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants submit this Letter pursuant to *M.P.E.P.* § 608.02(r), in order to propose a change to original Fig. 6 in this patent application. The proposed change is as follows:

In Fig. 6, add the designation --Prior Art--.

The proposed change is illustrated in red in the attached copy of Fig. 6 as originally filed.


No new matter is contained in the proposed drawing change.

The Examiner's approval of this proposed drawing change is respectfully requested.

Respectfully submitted,

SMITH, GAMBRELL & RUSSELL, LLP

By:


Michael A. Makuch, Reg. No. 32,263
1850 M Street, N.W., Suite 800
Washington, D.C. 20036
Phone: (202) 263-4300
Facsimile: (202) 263-4329

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